

What is claimed is:

1. In the fabrication of semiconductor integrated circuits, a ventilation system, comprising:
 - (a) a sleeve device having at least one aperture thereon for gas transfer;
 - (b) a ventilator coupled to the sleeve device; and
 - (c) a sensor coupled to the sleeve device.
2. The ventilation system of claim 1, wherein the sleeve device comprises a first and a second sleeve connected thereto.
3. The ventilation system of claim 2, wherein the sensor is coupled to the second sleeve.
4. The ventilation system of claim 3, wherein the sensor is adapted to generate a signal to control the ventilator when the sensor senses a relative movement between the first sleeve and the second sleeve.
5. The ventilation system of claim 1, wherein the at least one aperture is on an inner wall of the sleeve device.
6. The ventilation system of claim 1, wherein the sleeve device is connected to a pipeline.
7. The ventilation system of claim 6, wherein the sleeve device is adjacent to a gas outlet that is connected to the pipeline.
8. The ventilation system of claim 7, wherein the sleeve device and the pipeline are substantially coaxial.
9. The ventilation system of claim 1, wherein the ventilator is coupled to an outer wall of the sleeve device.

10. The ventilation system of claim 7, wherein the sensor is adapted to generate a signal to control the ventilator when the sensor senses a relative movement between the sleeve device and the gas outlet.

11. In the fabrication of semiconductor integrated circuits, a ventilation system, comprising:

(a) a sleeve device connected to a pipeline, having at least one aperture on an inner wall thereof;

(b) a ventilator coupled to an outer wall of the sleeve device; and

(c) a sensor coupled to the sleeve device.

12. The ventilation system of claim 11, wherein the sleeve device comprises a first and a second sleeve connected thereto.

13. The ventilation system of claim 12, wherein the sensor is coupled to the second sleeve.

14. The ventilation system of claim 13, wherein the sensor is adapted to generate a signal to control the ventilator when the sensor senses a relative movement between the first sleeve and the second sleeve.

15. The ventilation system of claim 11, wherein the sleeve device is adjacent to a gas outlet that is connected to the pipeline.

16. The ventilation system of claim 11, wherein the sleeve device and the pipeline are substantially coaxial.

17. The ventilation system of claim 15, wherein the sensor is adapted to generate a signal to control the ventilator when the sensor senses a relative movement between the sleeve device and the gas outlet.

18. In the fabrication of semiconductor integrated circuits, a method of ventilation, comprising:

(a) sensing a relative moving between a sleeve having at least aperture for gas transfer and a gas outlet connected to a pipeline; and

(b) generating a signal to control a ventilator when the relative moving between the sleeve and the gas outlet is sensed.

19. The method of claim 18, wherein the step (a) further comprises moving the sleeve toward the gas outlet along the pipeline.

20. The method of claim 19 further comprising venting the gas from the gas outlet.

21. The method of claim 20 further comprising venting the gas through the at least one aperture and between inner and outer walls of the sleeve.